

**TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT**

(Under 37 CFR 1.97(b) or 1.97(c))

Docket No.

US 6,875

In Re Application Of: Young-Guo LEE et al.

JUL 30 2003

PATENT &amp; TRADEMARK OFFICE

AUG -1 2003  
TECHNOLOGY CENTER 2800Serial No.  
10/029,147Filing Date  
December 28, 2001Examiner  
TBAGroup Art Unit  
2812Title: **METHOD OF FABRICATING SEMICONDUCTOR DEVICE FOR PREVENTING CONTAMINATING PARTICLE GENERATION**

Address to:

Assistant Commissioner for Patents  
Washington, D.C. 20231**COPY****37 CFR 1.97(b)**

1. ☒ The Information Disclosure Statement submitted herewith is being filed within three months of the filing of a national application other than a continued prosecution application under 37 CFR 1.53(d); within three months of the date of entry of the national stage as set forth in 37 CFR 1.491 in an international application; before the mailing of a first Office Action on the merits, or before the mailing of a first Office Action after the filing of a request for continued examination under 37 CFR 1.114.

**37 CFR 1.97(c)**

2. ☐ The Information Disclosure Statement submitted herewith is being filed after the period specified in 37 CFR 1.97(b), provided that the Information Disclosure Statement is filed before the mailing date of a Final Action under 37 CFR 1.113, a Notice of Allowance under 37 CFR 1.311, or an Action that otherwise closes prosecution in the application, and is accompanied by one of:

☐ the statement specified in 37 CFR 1.97(e);**OR**☐ the fee set forth in 37 CFR 1.17(p).

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Group Art Unit

2812

**METHOD OF FABRICATING SEMICONDUCTOR DEVICE FOR PREVENTING  
PARTICLE GENERATION**

**COPY**

**Payment of Fee**

(Only complete if Applicant elects to pay the fee set forth in 37 CFR 1.17(p))

- ☐ A check in the amount of \_\_\_\_\_ is attached.
- ☐ The Assistant Commissioner is hereby authorized to charge and credit Deposit Account No. \_\_\_\_\_ as described below. A duplicate copy of this sheet is enclosed.
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Dated: MARCH 31, 2003

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APPLICANT: Young-Goo Lee et al.

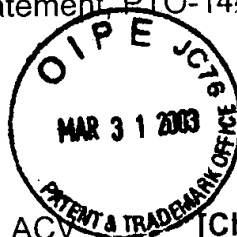
SERIAL NO.: 10/029,147

FILING DATE: December 28, 2001

TITLE: METHOD OF FABRICATING SEMICONDUCTOR DEVICE FOR  
PREVENTING CONTAMINATING PARTICLE GENERATION

RECEIPT OF THE FOLLOWING PAPERS IS ACKNOWLEDGED:

Transmittal of Information Disclosure Statement, PTO-1449 Form,  
1 reference.



DATE: March 31, 2003

ATTY: ACV [Check No. N/A]